

# Computational modelling of nanowire growth

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# Introduction

# Background

- Semiconducting nanowires are small crystalline filaments with diameters in the order of a few nanometres.
- Usually made of type III-V semiconductors, such as GaAs or InP.
- They are interesting because they show many potential applications.

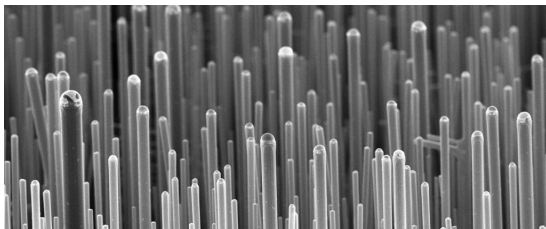


Figure: <https://www.cvdequipment.com/portfolio-item/silicon-nanowires-sem-10-k-x/>

# Application: Majorana zero modes

- They can be used to implement the Majorana chain.
- Nanosystem with topological phase that shows applications in topological quantum computing.
- Solves the decoherence problem by creating topologically-protected qubits.

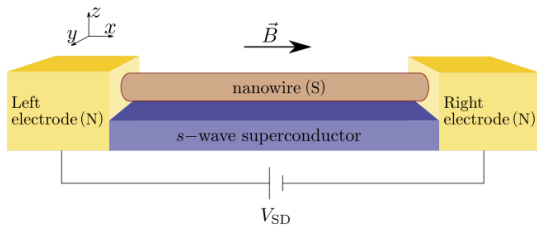


Figure: <https://arxiv.org/pdf/1902.05821.pdf>

# Nanowire growth

- There are many different procedures for growing semiconducting nanowires.
- One of them is selective area epitaxy (SAE).

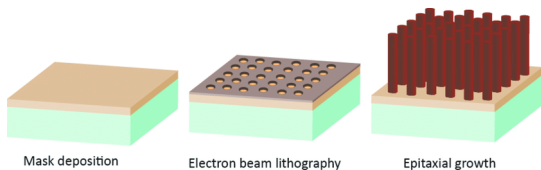
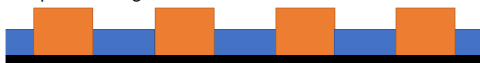


Figure: <https://www.researchgate.net/publication/303682098>

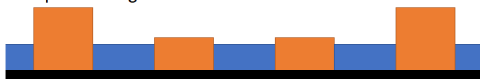
# Experimental observations

- It has been observed experimentally that sometimes nanowires grow unevenly.
- Three distinct growth regimes can be identified

Independent regime



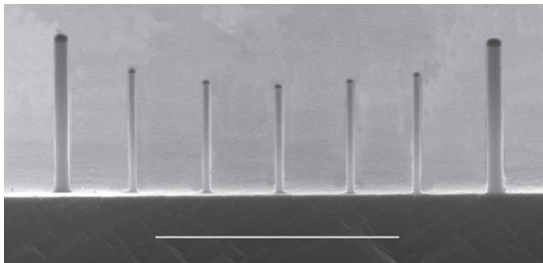
Competitive regime



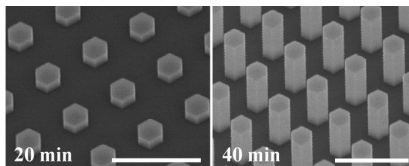
Synergetic regime



# Experimental observations



*Figure: Borgstrom, M. et al - Synergetic nanowire growth (Nature nanotechnology)*



*Figure: <https://aip.scitation.org/doi/10.1063/1.4916347>*

# Motivation

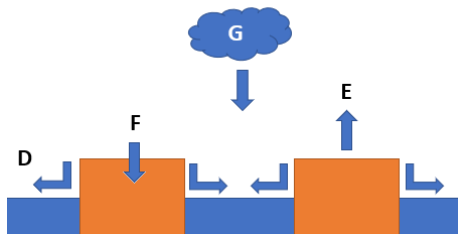
- A simple model for selective area epitaxy may provide qualitative information about the origin of these regimes.
- Knowing their origin can provide information on the underlying mechanisms for nanowire growth.
- For example, optimization: How can synergy be effectively suppressed?



# The model

# MBE

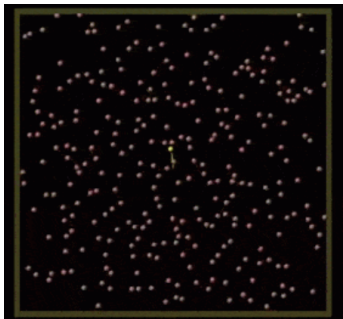
We can highlight some elements when modelling a SAE process:



- $G$ : Number of particles adsorbing to the system per unit time
- $F$ : probability of an adatom to nucleate into the semiconductor.
- $E$ : probability of an adatom to evaporate back.
- $D$ : tendency of the system to equilibrate concentrations.

## Proposed models

→ We could model the paths of the particles with a random walk;



→ But it is more practical to postulate and solve a differential equation.

# The diffusion equation

- The equations that model particles in diffusion are the Fick laws.

$$J = -D \cdot \nabla c \quad \text{First Fick law,}$$

$$\frac{\partial c}{\partial t} = \nabla(D \cdot \nabla c) \quad \text{Second Fick law.}$$

- The most useful equation is the second Fick law in steady-state form.

$$\nabla(D \cdot \nabla c) = 0$$

- Needs the *quasistatic* approximation: equilibrium much faster than growth.

# The model

- We can add a source term for the incoming particles and sink terms for the loss of adatoms.

$$\nabla(D \cdot \nabla c) - (E + F) \cdot c + G = 0$$

- Note that the diffusion constant depends on characteristic time and characteristic length.

$$D = \frac{L^2}{4t}$$

- The definition of the characteristic time enables us to redefine the parameters and the equation in a more physically meaningful way.

$$E + F = \frac{1}{t}$$

$$\nabla \left( \frac{L^2}{4t} \cdot \nabla c \right) - \frac{c}{t} + G = 0$$

# Temperature

→ Temperature may be introduced through Arrhenius law.

$$A \rightarrow A(T) = A \exp\left(-\frac{E_a}{K_B T}\right)$$

→ Should work for  $D$ , but what about  $L$ ,  $t$  and  $G$ ? Values for  $E_a$ ?

→ Observe how  $A = A(T \rightarrow \infty)$

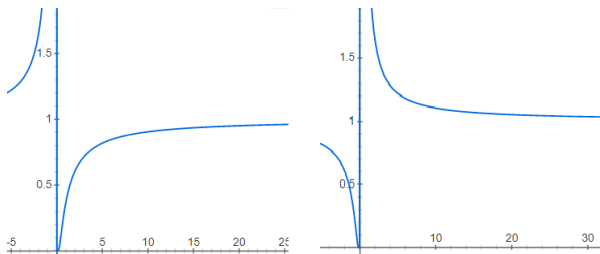
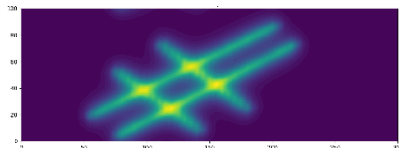
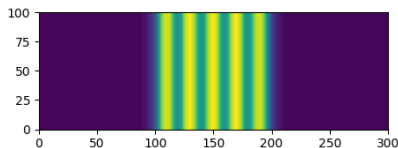


Figure: Plots for  $\exp \frac{-1}{x}$  and  $\exp \frac{1}{x}$

# Approach

# Solving the equation numerically

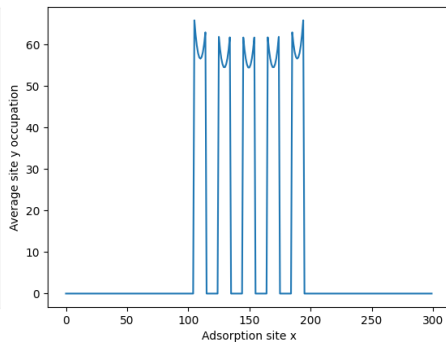
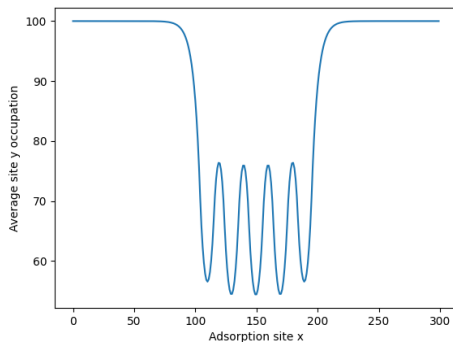
- Use of a finite-element solver with periodic boundary conditions.
- The result of the equation is the steady-state distribution of adatoms in the surface, proportional to the nanowire growth rate.
- The equation can be solved for an arbitrary trench geometry. However, for rectilinear trenches the process is computationally more efficient and more insightful.





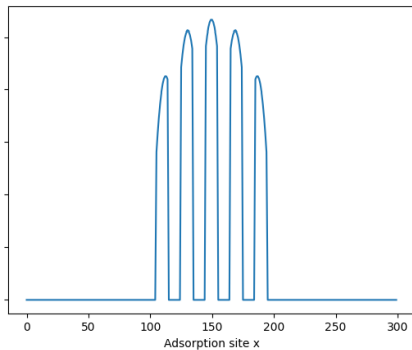
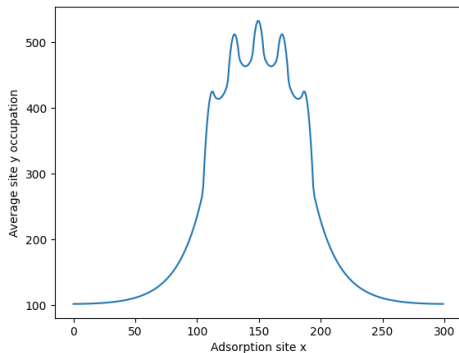
# Solving the equation numerically

For some parameter values the resulting regime is competitive...



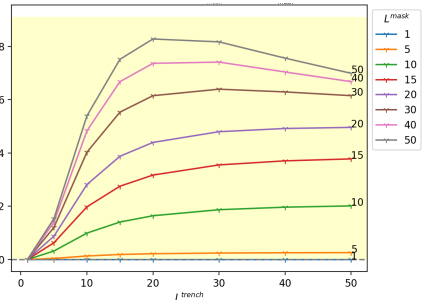
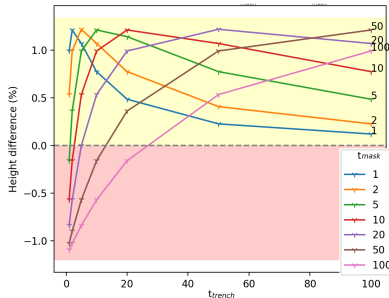
# Solving the equation numerically

...while for others is synergetic



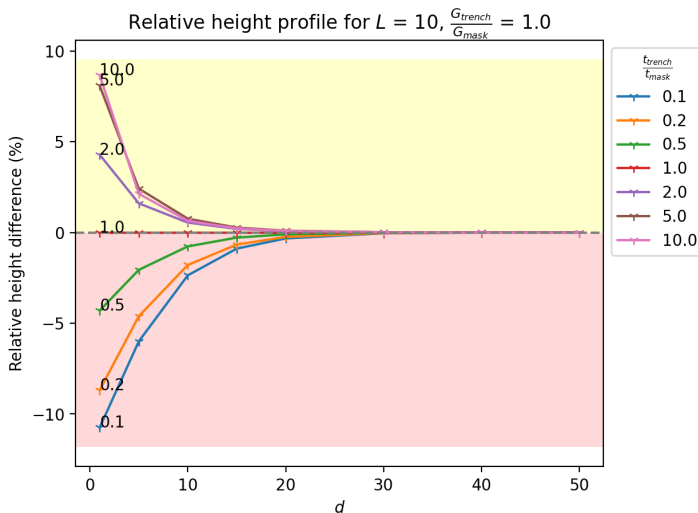
# Characterizing the regimes

- To characterize the growth regimes, we can use the difference in nanowire heights  $r = h_1 - h_0$ . Material volume could also be used.
- Plot  $r$  for different values of  $(d, t, L, G)$ , fixing two of them.
- For the parameters  $t$  and  $G$  we consider the ratios between mask and trenches, while for  $L$  and  $d$  we consider the values.

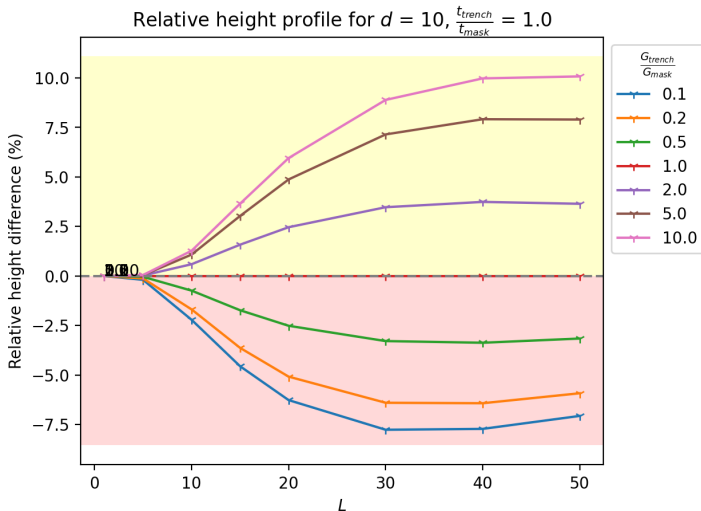


# Results

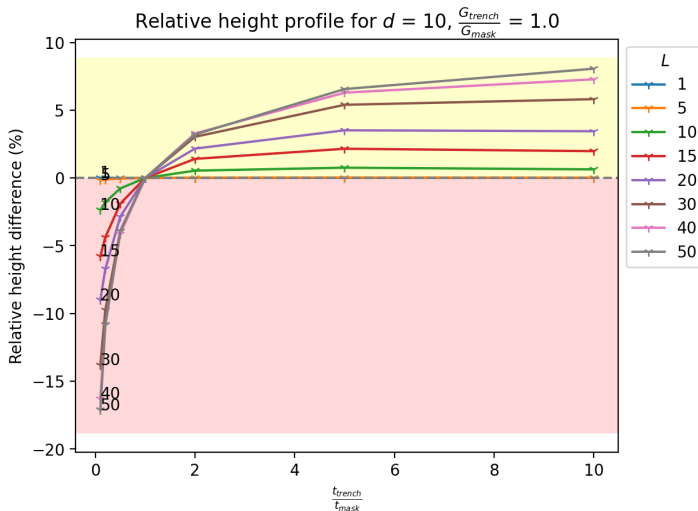
# The role of the nanowire separation



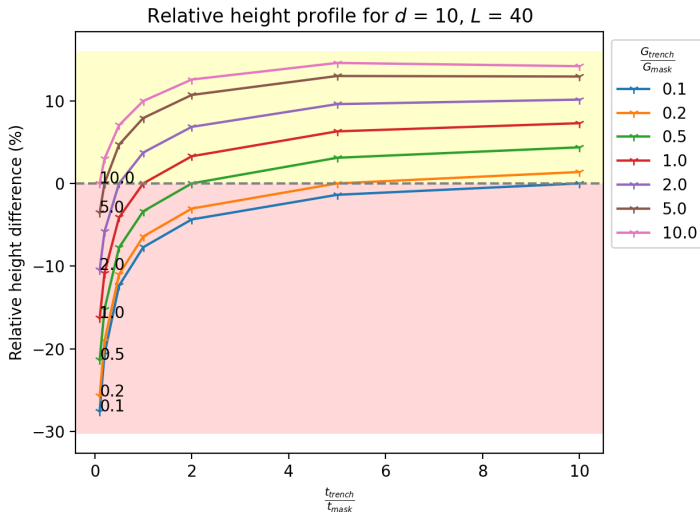
# The role of the characteristic length



# The role of the characteristic time



# The role of the input flux





# Conclusions

# Conclusions

- The simple model apparently captures the three regimes depending on two factors.
  - On the one hand: relative adatom density. Characterized by  $t$  and  $G$ .
  - On the other hand: adatom diffusion. Characterized by  $L$  and  $d$ .
  - Many potential generalizations (temperature, geometries, more complex model...).
- 
- **Is this numerical characterization useful for a real process?**
  - **With the right parameters, does it reflect experiment?**

# Questions?

*Thank You!*